

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE <sup>3723</sup>

Applicants: Eran Dvir, Eli Haimovich and Benjamin Shulman <sup>#19</sup>  
Assignee: Nova Measuring Instruments Ltd <sup>#IDS 11/26/98</sup>  
Title: APPARATUS FOR OPTICAL INSPECTION OF WAFERS DURING POLISHING  
Serial No.: 08/497,382 Filed: June 29, 1995  
Examiner: E. Morgan Group Art Unit: 3203  
Batch No.: U26 Allowed: November 17, 1997  
Docket No.: M-3417 US

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COMMISSIONER OF PATENTS AND TRADEMARKS  
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July 27, 1998

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INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, Applicants bring the following documents (copies enclosed) to the Examiner's attention in the above-captioned application. Although the Examiner may not consider these documents, Applicants request that they be placed in the file.

1. European Patent Publication No. 0 493 117 A2 dated 07/01/92
2. European Patent Publication No. 0 663 265 A1 dated 07/19/95
3. Japanese Patent Publication No. 60 018925 dated 01/31/85 (Abstract)

A PTO form 1449 listing these documents is enclosed.

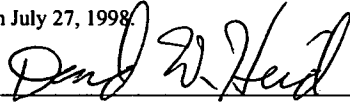
Citation of the above documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;

2. a representation that a search has been made, other than as described above; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231,

on July 27, 1998.



Attorney for Applicant(s)

27 July 98

Date of Signature

Respectfully submitted,



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